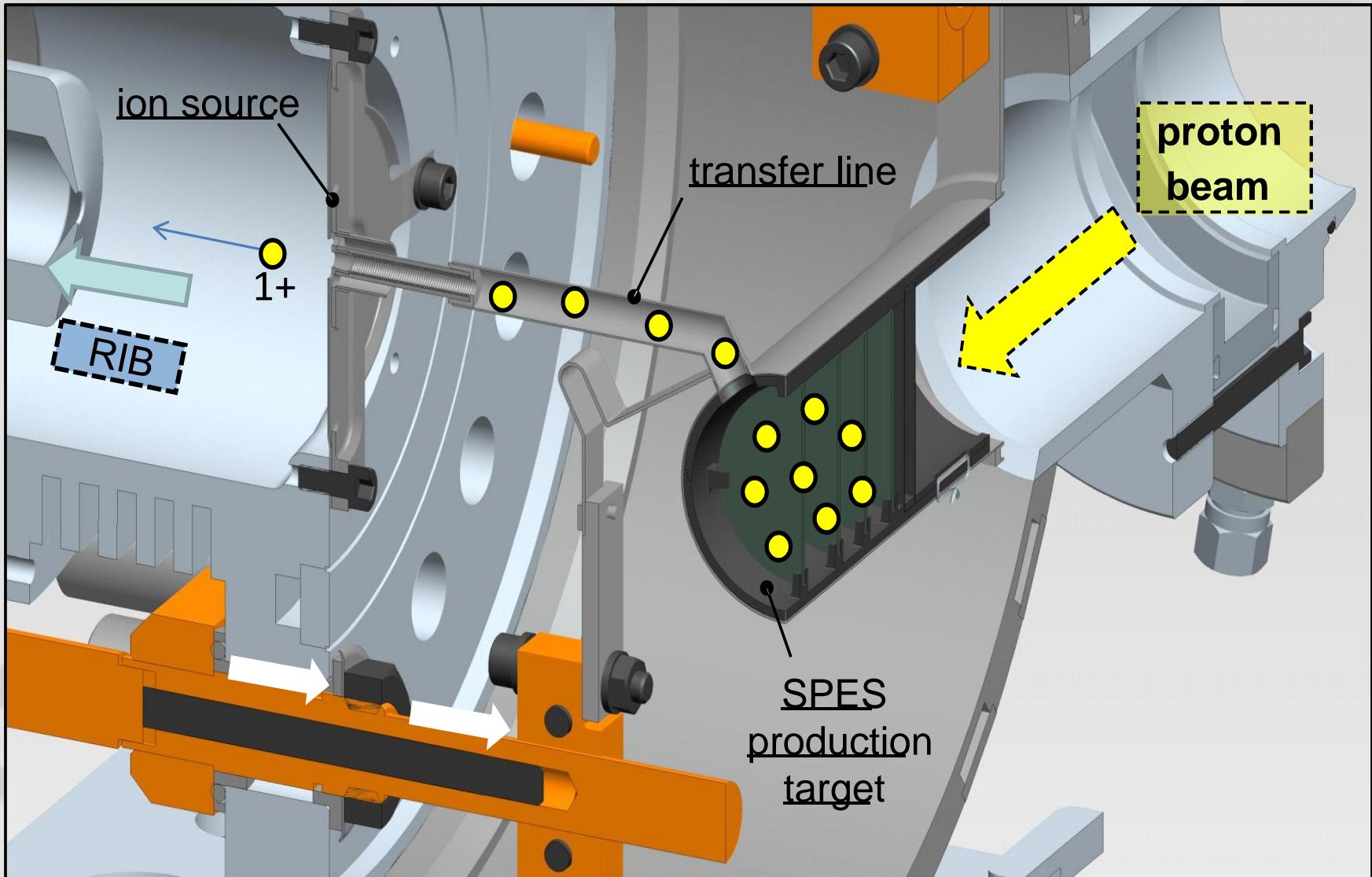


p-rich beams for SPES- α

Alberto Andrigetto
LNL-INFN

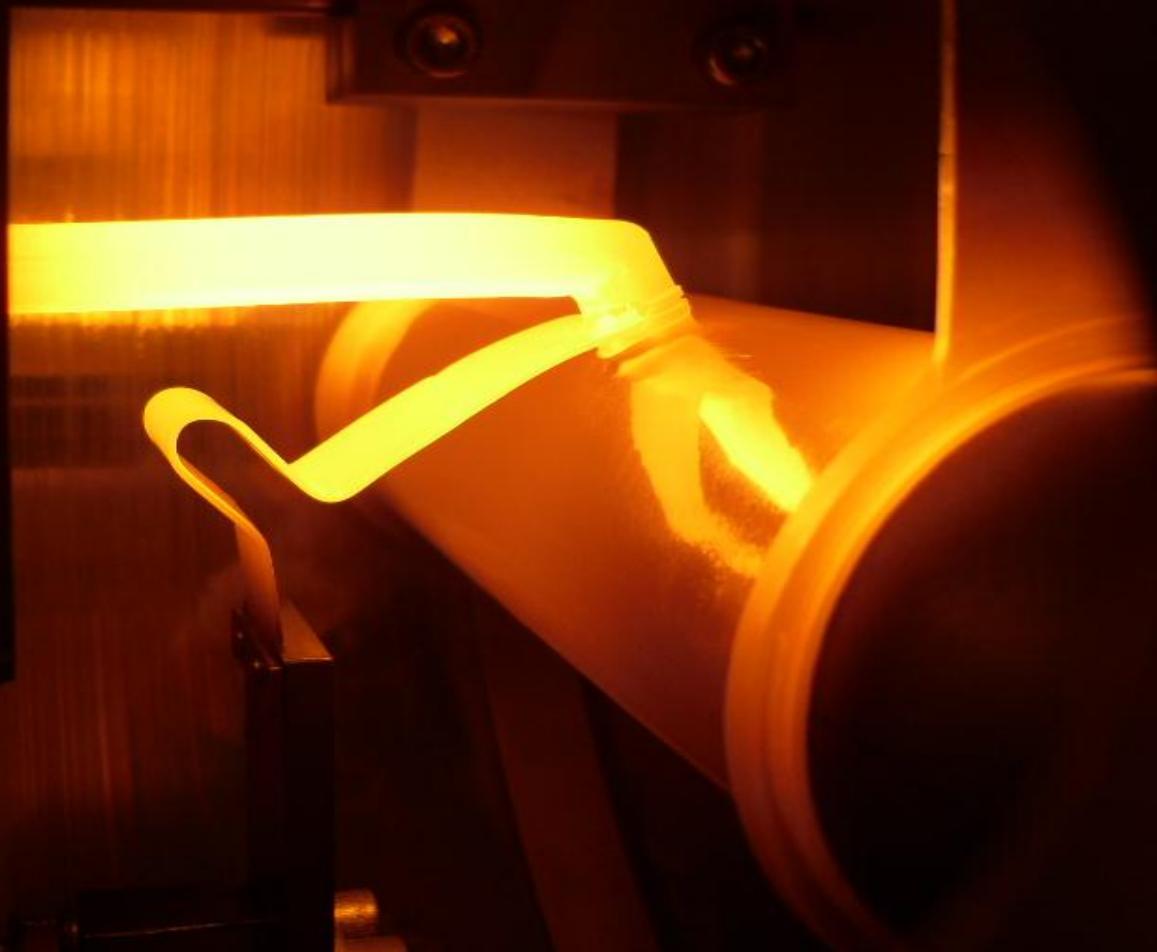
The SPES TIS complex



The Target: ready for irradiation...

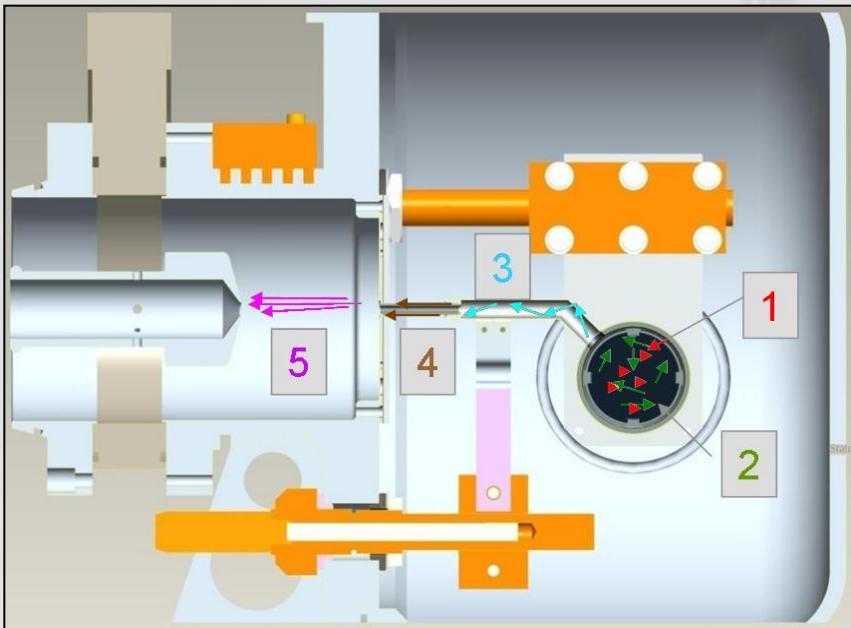
$I_{\text{Target}} = 700\text{A} \rightarrow 1200\text{A max}$

$I_{\text{Line}} = 200\text{A} \rightarrow 600\text{A max}$



The isotope release

Release of isotopes from a ISOL target: involved processes



1. In-target reaction (fission)
2. In-target diffusion
3. Effusion from target to ion source
4. Ionization
5. Acceleration and transport

The target yield and release efficiency

$$Y_{\text{Target}} = \Phi \cdot \sigma \cdot N \cdot \varepsilon_R$$

Φ = Injector flux, σ = Cross section
 N = Target thickness, ε_R = Release efficiency

ε_R takes into account the efficiencies of all the involved processes

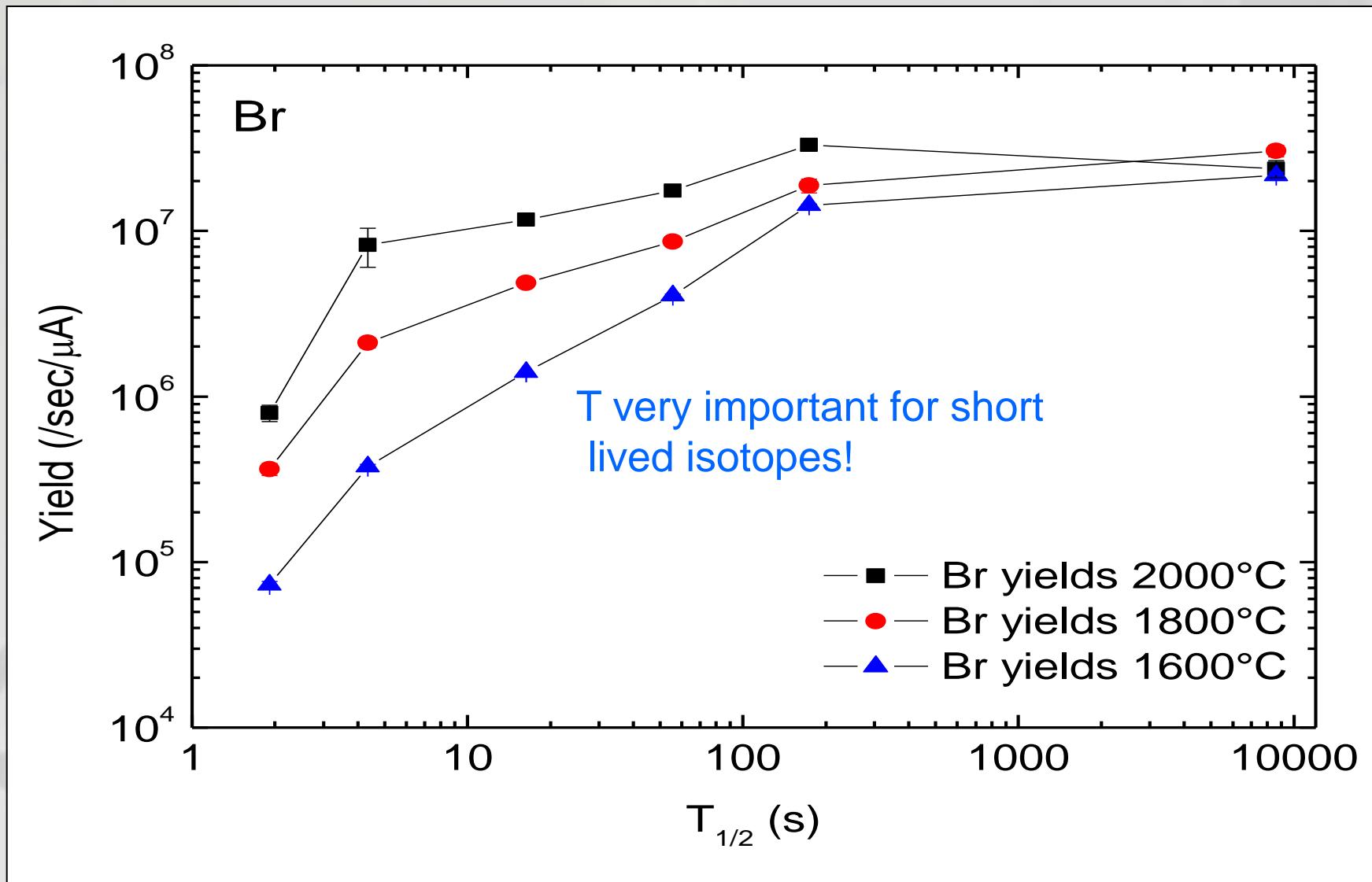
$$\varepsilon_R = \varepsilon_{\text{diffusion}} \cdot \varepsilon_{\text{effusion}} \cdot \varepsilon_{\text{ionization}} \cdot \varepsilon_{\text{transport}}$$

Most critical processes for release efficiency, they are affected by:

- 1) Material composition and density
- 2) Material microstructural properties (grain size, porosity, interconnectivity)
- 3) Working Temperature (use of high limiting temperature materials)

Temperature vs yield ...

Spes data from HRIBF measurement



First conclusion...

Is necessary to produce for SPES RIB:

- 1) Target with high working temperature ->
refractory carbides/oxides

- 2) Material with good characteristics in
terms of release (grain and porosity) ->
carefully R&D is mandatory!

Target: n-rich vs. p-rich

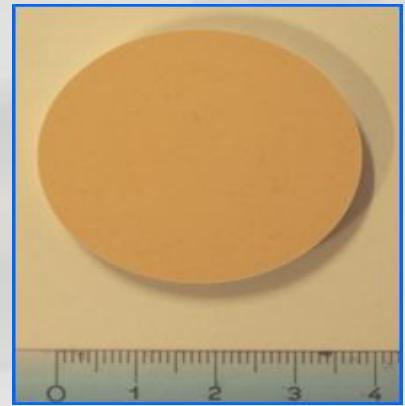
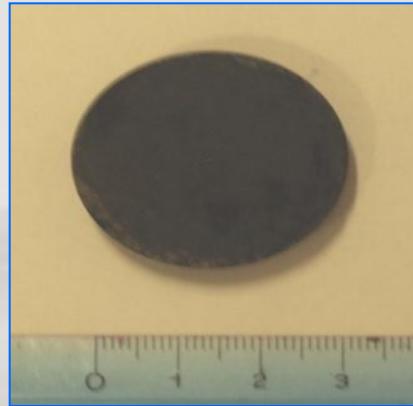
1 target material (UCx), &
many isotopes produced on it



	2010	2011	2012
Density (g/cm ³)	4.25	2.59	6.38
Diameter (mm)	12.50	13.07	12.91
Thickness (g/cm ²)	0.41	0.41	0.41
Calculated porosity (%)	58	75	37

Main challenging

Dedicated material (carbides), &
few isotopes produced in each

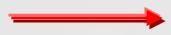


Lanthanum carbide synthesis

Vertical Carbothermic reduction (1600°C, high vacuum)

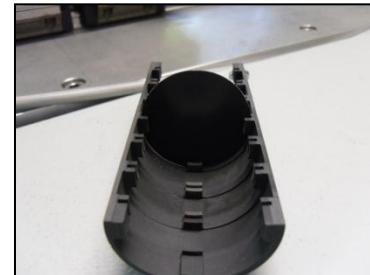
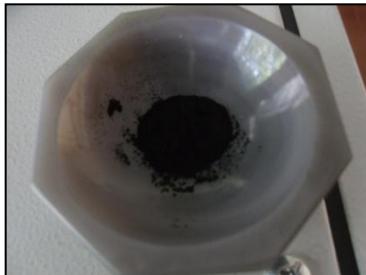


OXIDE + GRAPHITE GREEN PELLETS



CARBIDE/GRAHPE (LaCx) PELLETS

Boron carbide (B_4C) production



Solution of the acid

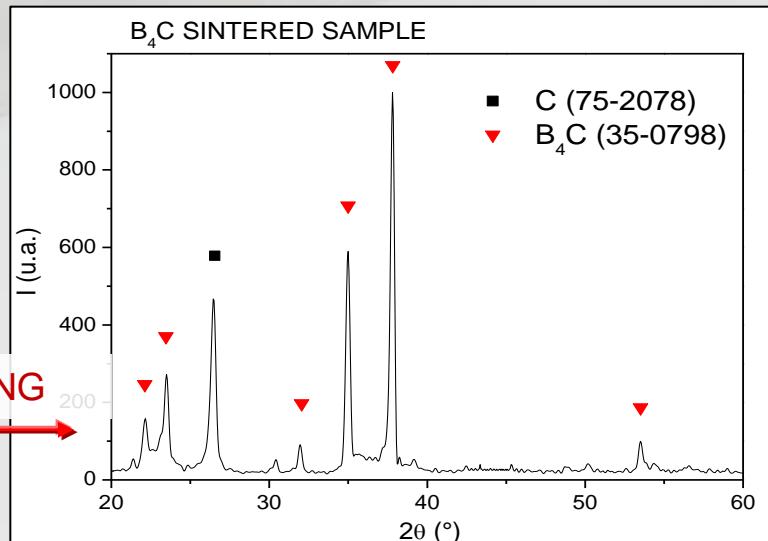
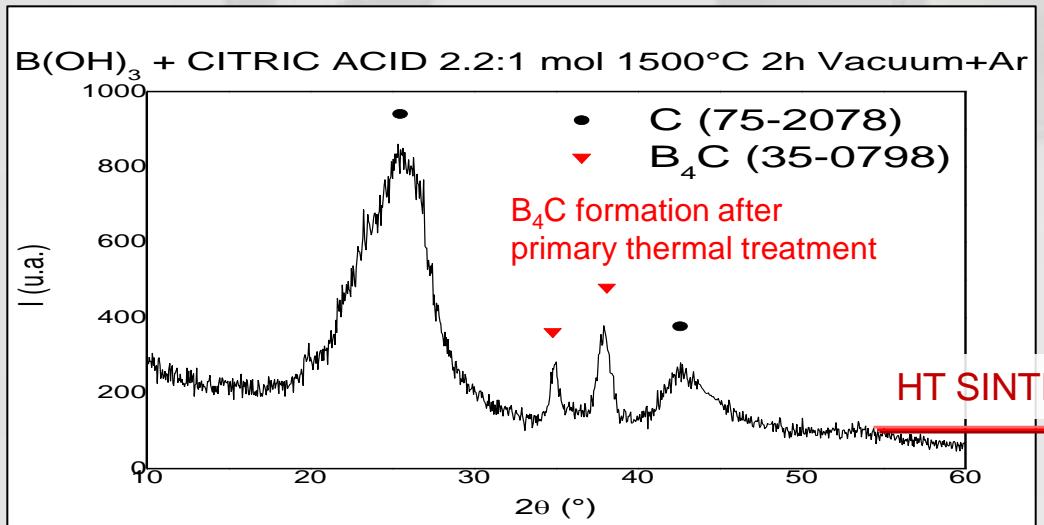
Gel formation

Grounding

Thermal treatment

High T sintering

- Thermal treatment :**
- up to 800°C in low vacuum (5×10^{-2} mbar), 0.5 °C/min
 - up to 1500°C in vacuum with Ar flow (1 mbar), 1÷3°C/min
 - 2 hours at 1500°C



Possible p-rich beams for SPES-a

1 H		 Alkaline - Alkaline earth metals		2 He
3 Li	4 Be	 Post-transition elements		
11 Na	12 Mg	 Halogens		
19 K	20 Ca	 Noble gases		
37 Rb	38 Sr	 Transition metals		
55 Cs	56 Ba		5 B	6 C
87 Fr	88 Ra		7 N	8 O
			9 F	10 Ne
			13 Al	14 Si
			15 P	16 S
			17 Cl	18 Ar
			34 Se	35 Br
			36 Kr	
			33 As	
			32 Ge	
			31 Ga	
			30 Zn	
			29 Cu	
			28 Ni	
			27 Co	
			26 Fe	
			25 Mn	
			24 Cr	
			23 V	
			22 Ti	
			21 Sc	
			40 Zr	
			41 Nb	
			42 Mo	
			43 Tc	
			44 Ru	
			45 Rh	
			46 Pd	
			47 Ag	
			48 Cd	
			49 In	
			50 Sn	
			51 Sb	
			52 Te	
			53 I	
			54 Xe	
		 Lanthanides		

57 La	58 Ce	59 Pr	60 Nd	61 Pm	62 Sm	63 Eu	64 Gd	65 Te	66 Dy	67 Ho	68 Er	69 Tm	70 Yb	71 Lu
89 Ac	90 Th	91 Pa	92 U	93 Np	94 Pu	95 Am	96 Cm	97 Bk	98 Cf	99 Es	100 Fm	101 Md	102 No	103 Lr

Target for light isotopes

Elemento	A	Half Life	Target dedicati	Ionizzazione
Na	21	22.48 s	Al ₂ O ₃ – SiC	SIS
Na	22	2.6 a	Al ₂ O ₃ – SiC	SIS
Mg	22	3.86 s	Al ₂ O ₃ – SiC	LIS-FEBIAD
Mg	23	11.3 s	Al ₂ O ₃ – SiC	LIS-FEBIAD
Al	24	2.05 s	SiC	SIS-LIS
Al	25	7.18 s	SiC	SIS-LIS
Al	26	6.35 s	SiC	SIS-LIS
P	29	4.1 s	SiC - CeS	FEBIAD

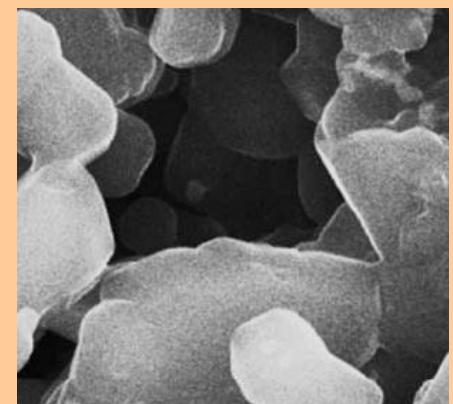
SiC (Saint Gobain)



$^{28}\text{Si}(\text{p},\alpha)^{25}\text{Al}$ $^{28}\text{Si}(\text{p},2\text{pn})^{26}\text{Al}$

Elemento	A	Half Life	Target dedicati	Ionizzazione
Be	7	53.29 d	B ₄ C	LIS
F	17	64.8 s	ZrO ₂ – HfO ₂	FEBIAD
F	18	109.7 m	Al ₂ O ₃	FEBIAD
Si	26	2.21 s	Al ₂ O ₃	FEBIAD
Si	27	4.16 s	Al ₂ O ₃	FEBIAD

Boron Carbide



Target for heavy isotopes

Elemento	A	Half Life	Target dedicati	Ionizzazione
I	126	13.11d	LaCx - CeS	FEBIAD
Xe	127	36.4 d	CeS	FEBIAD
Cs	129	32 h	CeS	SIS
Cs	130	29.2 m	LaCx - CeS	SIS
Cs	131	9.69 d	LaCx - CeS	SIS
Cs	132	6.47 d	LaCx - CeS	SIS
Ba	131	11.5 d	LaCx - CeS	SIS

LaCx



Elemento	A	Half Life	Target dedicati	Ionizzazione
Ho	164	29 m	TaC	SIS
Tm	168	93.1 d	TaC	SIS
Yb	169	32 d	TaC	SIS
Lu	172	6.7 d	TaC	SIS
Lu	173	1.37 a	TaC	SIS
Lu	174	3.31 a	TaC	SIS
Hf	173	23.6 h	TaC	FEBIAD

TaC foam



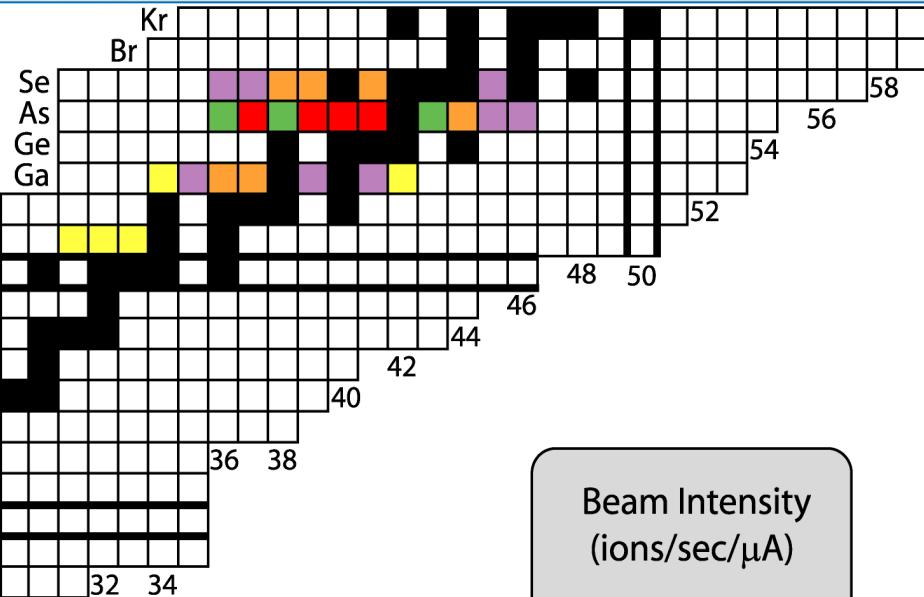
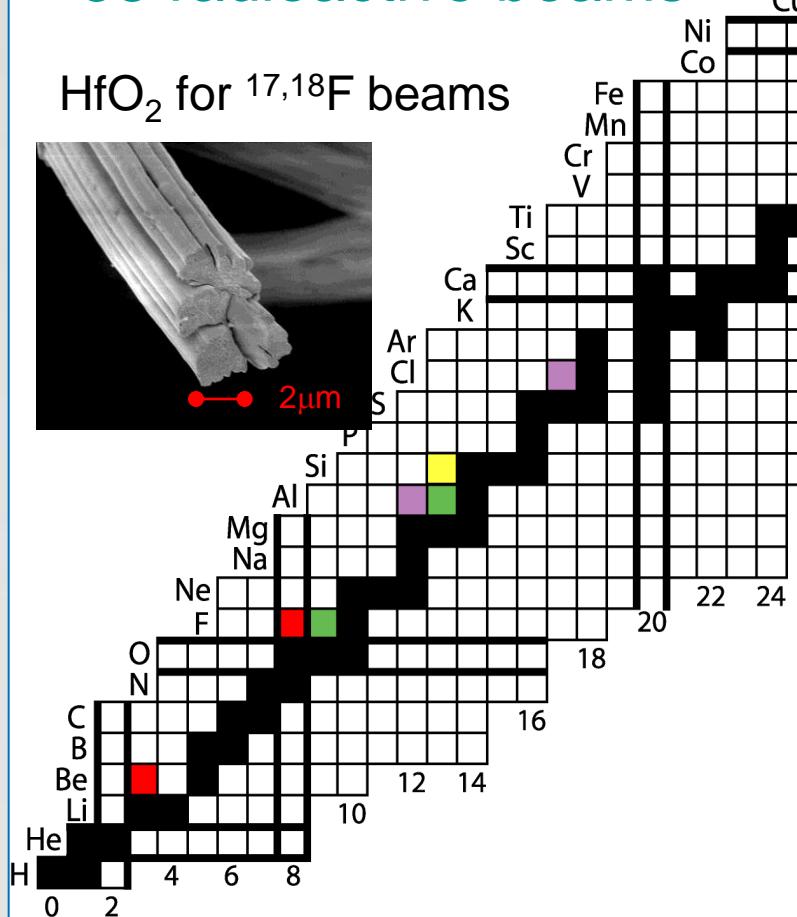
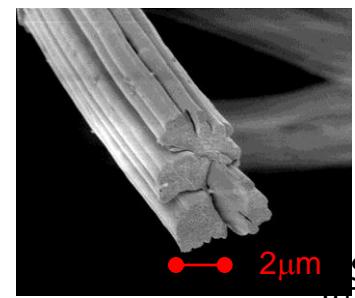
P-rich: production difficulty

Target material	Producible Elements	Ion Source	Material R&D effort needed	Beam quality
SiC	Al, Na, Mg, P	LIS-SIS-PIS	*	?
LaC _x	Cs, I, Ce, Ba	SIS-PIS	*	?
B ₄ C	Be	LIS-PIS	**	?
ZrC	As, Br, Rb, Sr	SIS-PIS	**	?
Al ₂ O ₃	Na, Mg, Si	LIS-SIS-PIS	***	?
HfO ₂ – ZrO ₂	F	PIS	***	?
CeS	P, Cl, La	PIS	****	?

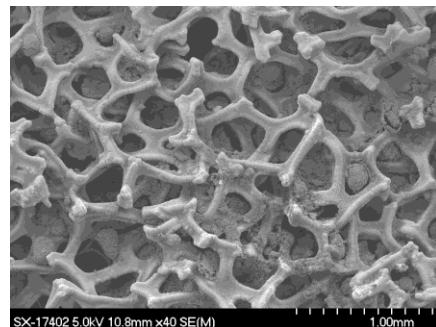
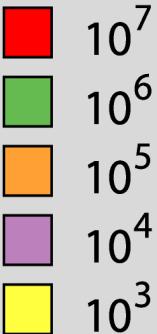
Proton-rich RIBS at HRIBF

- Seven different targets used
- Three different ion sources
- 33 radioactive beams

HfO₂ for ^{17,18}F beams



Beam Intensity
(ions/sec/μA)



CeS on RVC matrix for ³⁴Cl

Extrapolations for SPES...

(to be checked using dedicated codes..)

p-rich light isotopes...

Elements	$T_{1/2}$	Ion Source	Yield (1/s)	Target material
^{7}Be	53 d	LIS-PIS	$\sim 10^9$	B_4C
^{17}F	65 s	PIS	$\sim 10^9$	$\text{HfO}_2 - \text{ZrO}_2$
^{18}F	110 m	PIS	$\sim 10^8$	$\text{HfO}_2 - \text{ZrO}_2$
^{25}Al	7 s	LIS-PIS	$\sim 10^6$	SiC
^{26}Al	6 s	LIS-PIS	$\sim 10^8$	SiC
^{27}Si	4 s	LIS-PIS	$\sim 10^5$	SiC
^{34}Cl	32 m	PIS	$\sim 10^6$	CeS

What next for spes-alpha?

- ❖ Study of Isotope Yields from $p \rightarrow \text{Targ}_{\text{refractory}}$
- ❖ Study of Release from $p \rightarrow \text{Targ}_{\text{refractory}}$
- ❖ Yield Measurement of $p \rightarrow \text{Targ}_{\text{refractory}}$ @ different T (LNS?)

The SPES-TIS group

